

FORM PTO-1449 (SUBSTITUTE)

Attorney Docket No.:

Applic. No.

L&L-10078

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U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICE

Applicant

Alfred Kersch et al.

Filing Date

August 24, 2001

Group Art Unit

1762

INFORMATION DISCLOSURE
STATEMENT BY APPLICANT
(37 CFR 1.98(b))

U.S. PATENT DOCUMENTS

EXAMINER INITIALS		PATENT NO.	DATE	PATENTEE	CLASS	SUB CLASS	FILING DATE
	A	5,104,690	04/14/92	Greenwald			
	B	5,753,300	05/19/98	Wessels et al.			
	C						
	D						
	E						
	F						
	G						
	H						
	I						

FOREIGN PATENT DOCUMENT

		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB CLASS	TRANSL. YES NO
	J	60 026 663	02/09/85	Japan			X
	K						
	L						
	M						
	N						

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

	O	L.A. Wills et al.: "Deposition of Ferroelectric Bi ₄ Ti ₃ O ₁₂ Thin Films", <i>Extended Abstracts, Fall Meeting, Seattle, Washington, 90/2, 1990, p. 701, Princeton, NJ, XP-000294124</i>
	P	

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609;
Draw line through citation if not in conformance and not considered. Include copy of this form with
next communication to applicant.

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